

The ATLAS Insertable B-Layer (IBL) Project

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On behalf of the ATLAS IBL Collaboration



RD11

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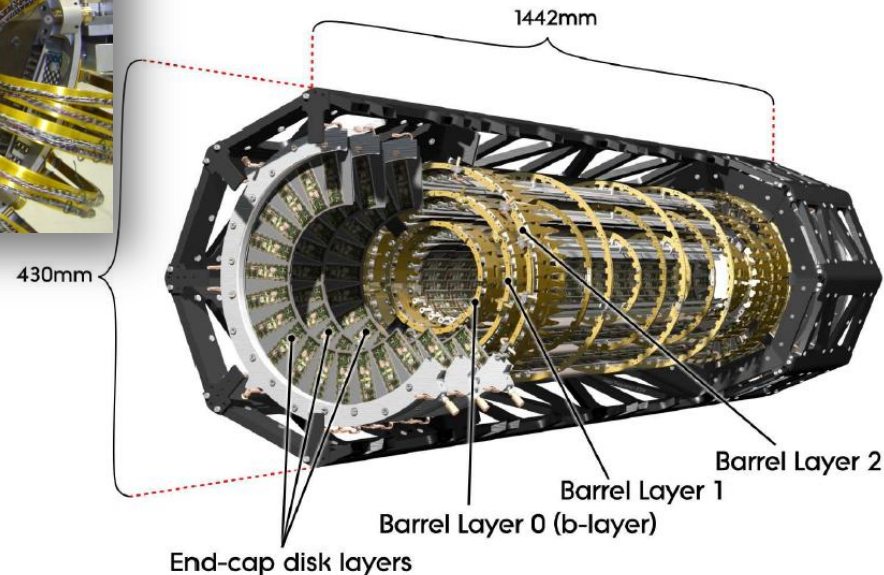
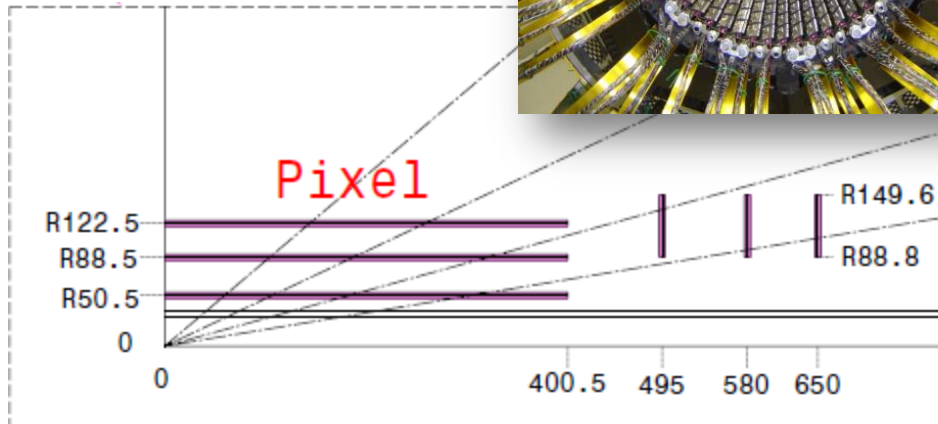
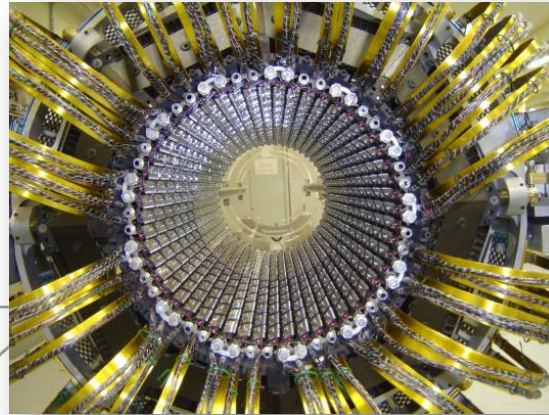
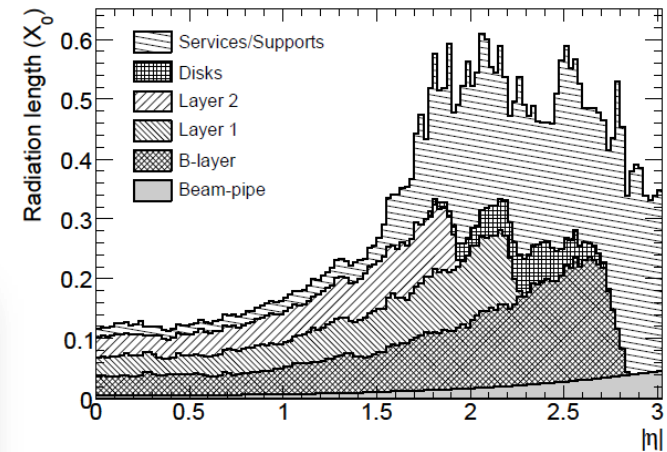
ATLAS Pixel Detector: Layout



Talk by D.Hirschbuehl

✓ Designed to provide at least 3 hits in $|\eta| < 2.5$

- 3 barrel + 3 forward/backward disks
- 112 staves with 13 modules each
- 48 sectors with 6 modules each
- 80 million channels
- $\sim 0.11 X_0$

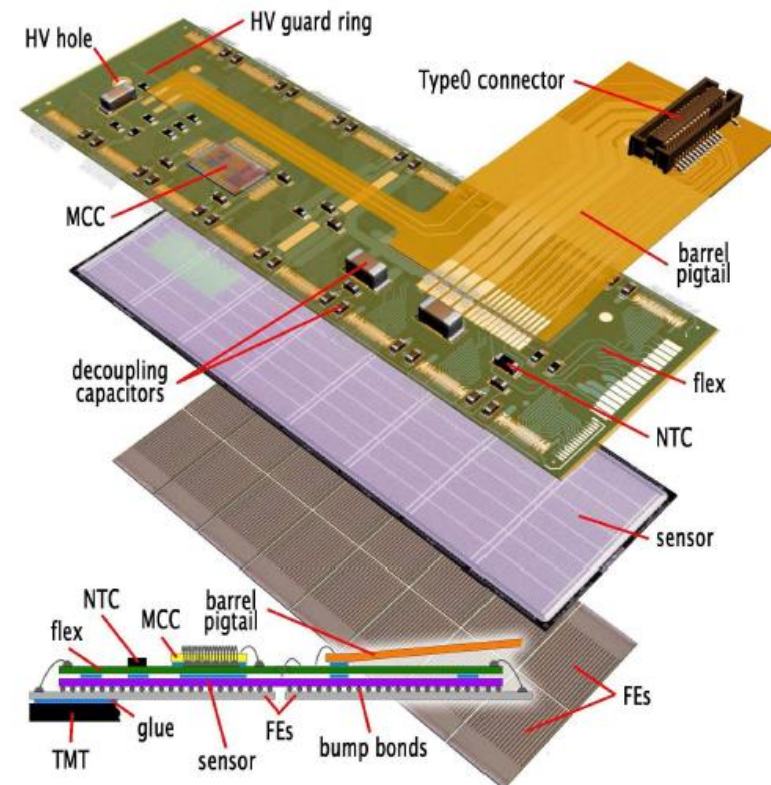


ATLAS Pixel Detector: Module



Talk by D.Hirschbuehl

- ✓ The building block of the detector is the module (1744 in total).
 - 16 Front-End chips (FE-I3) with a module controller (MCC), 0.25 μm technology.
 - 46080 R/O channels $50\mu\text{m}\times 400\mu\text{m}$
 - Planar n-in-n DOFZ silicon sensor 250 μm thick.
 - Readout speed 40-80 Mb/link
 - Designed for NIEL $1\times 10^{15} n_{eq}/\text{cm}^2$, 50 Mrad dose and a peak luminosity of $1\times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$
 - **Foreseen to replace the Pixel detector in ~2021 (HL-LHC).**

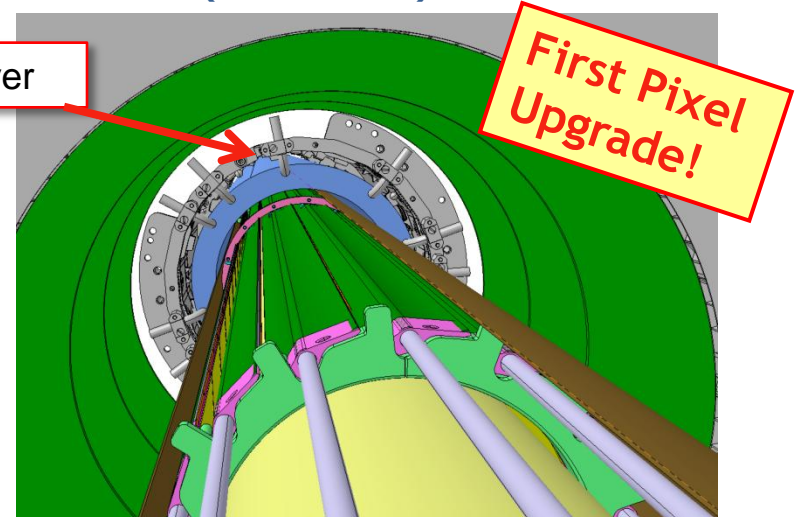
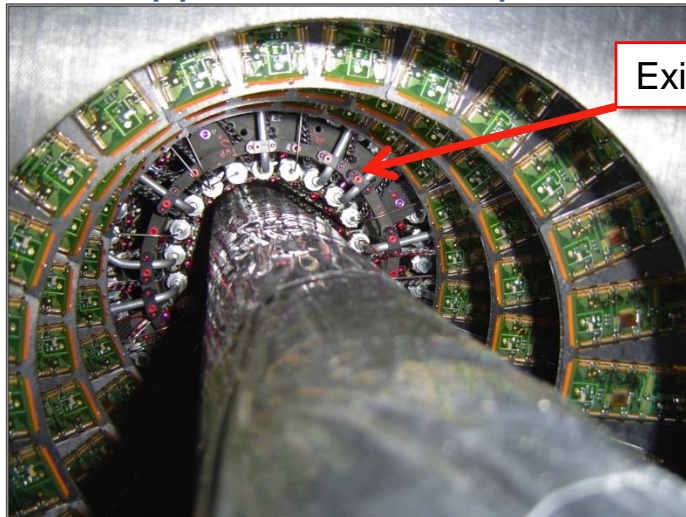


Dimensions: $\sim 2 \times 6.3 \text{ cm}^2$
Weight: $\sim 2.2 \text{ g}$

Insertable B-Layer: Project



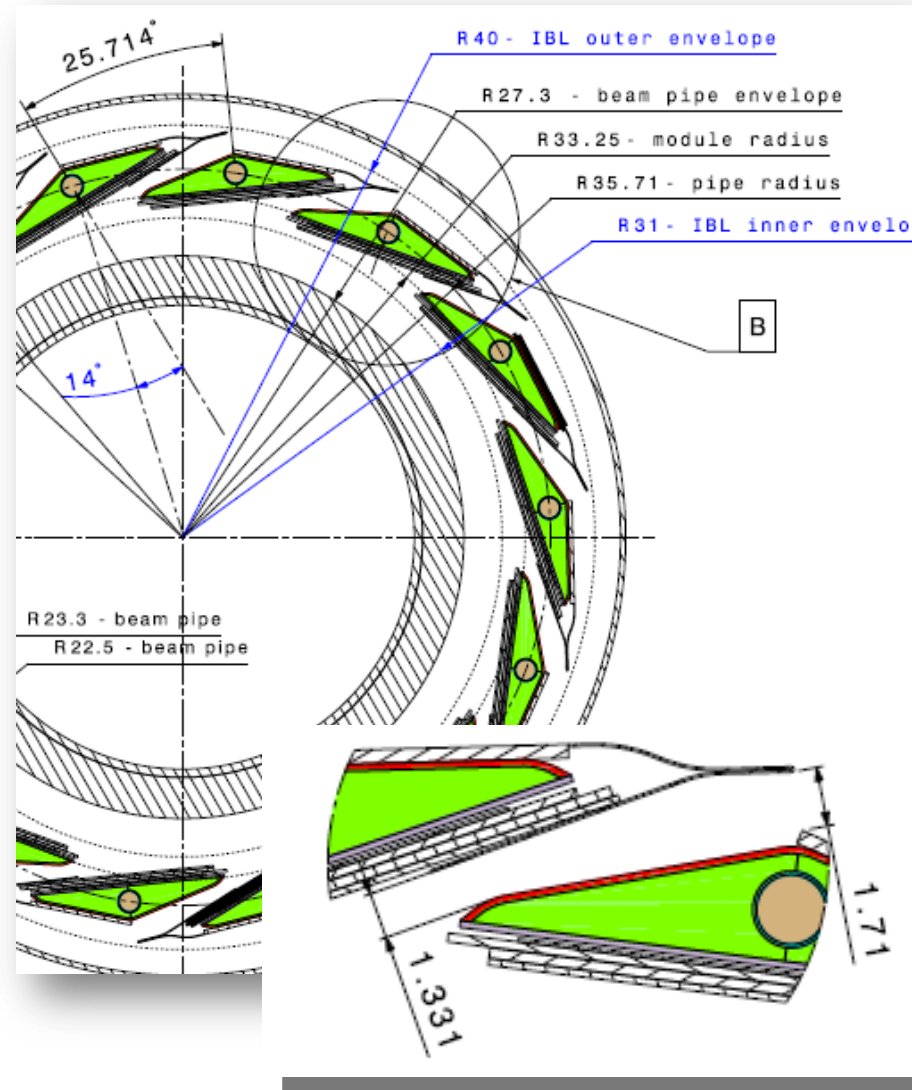
- ✓ The Pixel innermost layer (B-layer) was designed for replacement every 300 fb^{-1}
 - the requirements for replacibility in a long shutdown were released in the building phase.
 - New option (Feb 2009): to insert a new layer!
 - The envelopes of the existing Pixel detector and the beam pipe leave today a radial free space of 8.5 mm. The reduction of the beam-pipe radius of 5.5 mm brings it to 14 mm and make it possible.
 - The Insertable B-Layer IBL will be built around a new beam pipe and slipped inside the present detector in situ. O(9 months) needed.



Insertable B-Layer: Layout



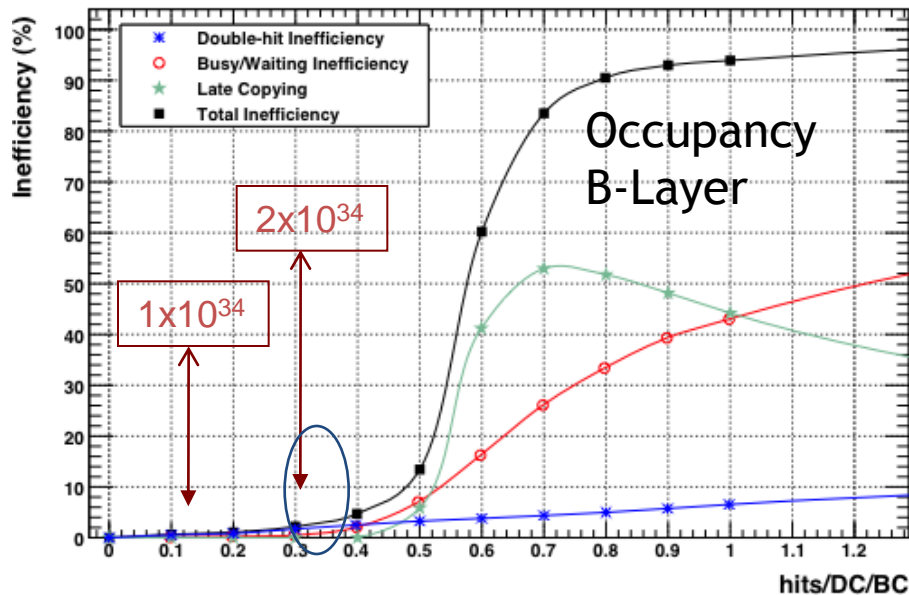
- ✓ Reduced Beam Pipe
 - Inner Radius 23.5 mm.
- ✓ Very tight clearance
 - Hermetic to straight tracks in ϕ
 - No overlap in z: minimum gap between sensor active area!
- ✓ Layout parameters:
 - IBL envelope : **9 mm in R!**
 - 14 staves
 - $\langle R_{\text{sens}} \rangle = 33$ mm
 - Total active length = 60 cm
 - Coverage in $|\eta| < 2.5$



Insertable B-Layer: Motivations



- ✓ Motivations for a 4th low radius layer in the Pixel Detector
 - Luminosity pileup
 - FE-I3 has 5% inefficiency at the B-layer occupancy for $2.2 \times 10^{34} \text{cm}^{-2}\text{s}^{-1}$
 - IBL improves tracking, vertexing and b-tagging for high pileup and recovers eventual failures in present Pixel detector.
 - Today the B-layer has 3.1% of inefficiency.



- Radiation damage
 - Degradation of the existing B-Layer reduce detector efficiency after 300-400 fb^{-1} . Not an issue as forecast for 2021 is $\sim 330 \text{fb}^{-1}$
- It serves also as a technology step towards HL-LHC.
- IBL Installation foreseen in 2013, during LHC first shutdown.

Insertable B-Layer: Performance



✓ b-tagging performance with IBL at $2 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$ is similar to current ATLAS without pileup

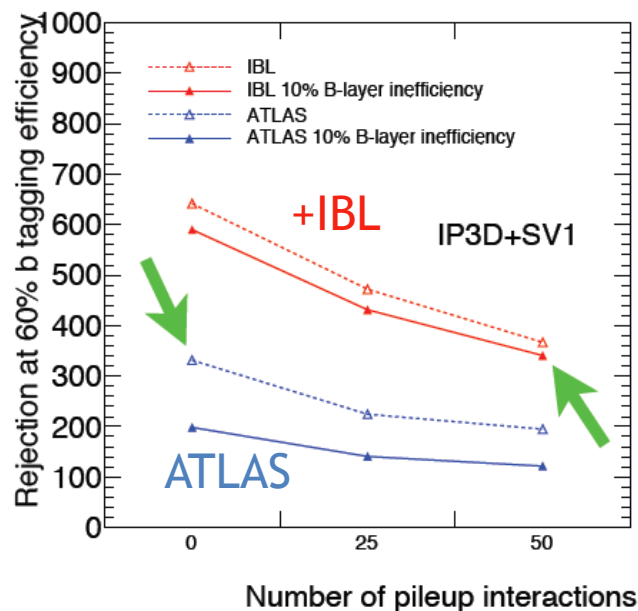
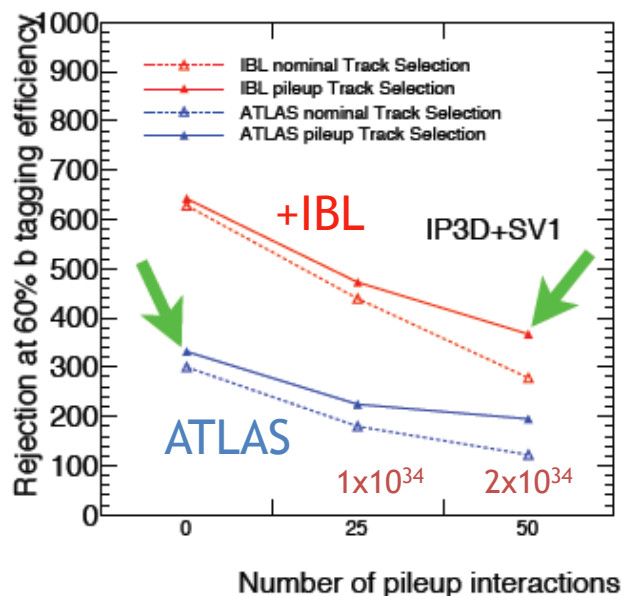


✓ Studied scenarios with detector defects, the IBL recovers the tracking and b-tagging performance.

- Shown 10% cluster inefficiency in B-layer.

- IBL fully recovers tracking efficiency.

- With IBL only small effect on b-tagging performance



Requirements for sensors/electronics

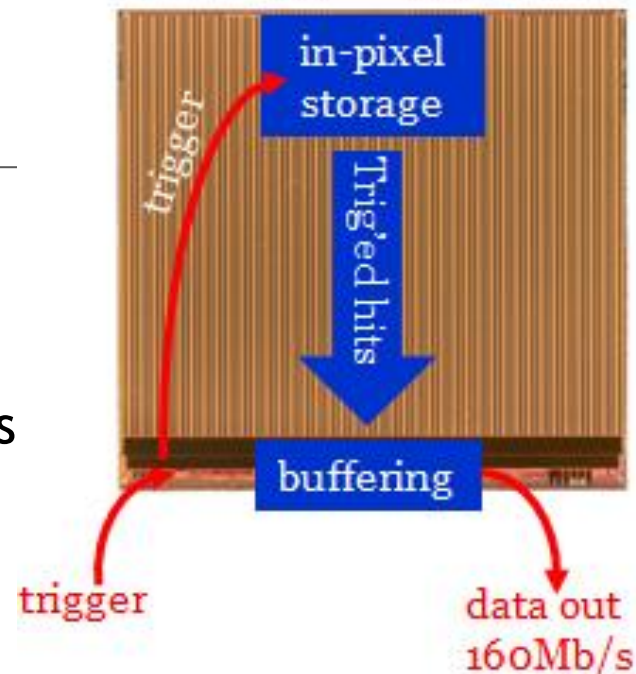


- ✓ IBL environment: Radiation hard FE and sensor.
 - Integrated luminosity seen by IBL = 550 fb^{-1} → Survive until to HL-LHC
 - IBL design peak luminosity = $3 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$
 - Design sensor/electronics for total dose:
 - NIEL dose = $3.3 \times 10^{15} \pm$ (“safety factors”) $\geq 5 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$
 - Ionizing dose $\geq 250 \text{ Mrad}$
- ✓ Two different pixel sensor technologies will be used:
 - n-in-n planar and 3D silicon detectors.
- ✓ Extra specifications:
 - Sensor HV: max 1000 V
 - Sensor Thickness: $225 \pm 25 \mu\text{m}$.
 - Sensor Edge width: below $450 \mu\text{m}$ (No shingling in z)
 - Tracking efficiency $> 97\%$
 - Sensor max power dissipation $< 200 \text{ mW}/\text{cm}^2$ at $T = -15 \text{ }^\circ\text{C}$
 - Operation with low ($\sim 1500e^-$) threshold.

X 5 the Pixel detector

FE electronics

- ✓ Reason for a new FE design:
 - Increase rad hardness
 - Reduce inefficiency at high luminosity
- ✓ New logic: instead of moving all the hits in EOC (FE-I3), store the hits locally in each pixel and distribute the trigger.
- ✓ Advantages:
 - Only 0.25% of pixel hits are shipped to EoC → DC bus traffic “low”.
 - Save digital power
 - Take higher trigger rate
 - At 3×LHC full lumi, inefficiency: ~0.6%
- ✓ This requires local storage and processing in the pixel array
 - Possible with smaller feature size technology (130 nm)
- ✓ Biggest chip in HEP to date: 4 cm²

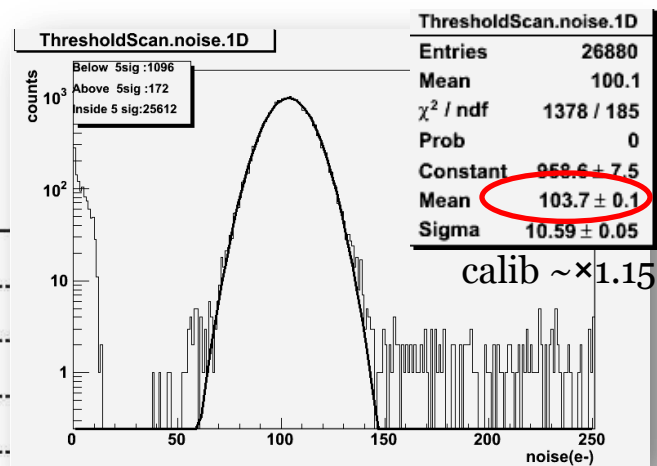
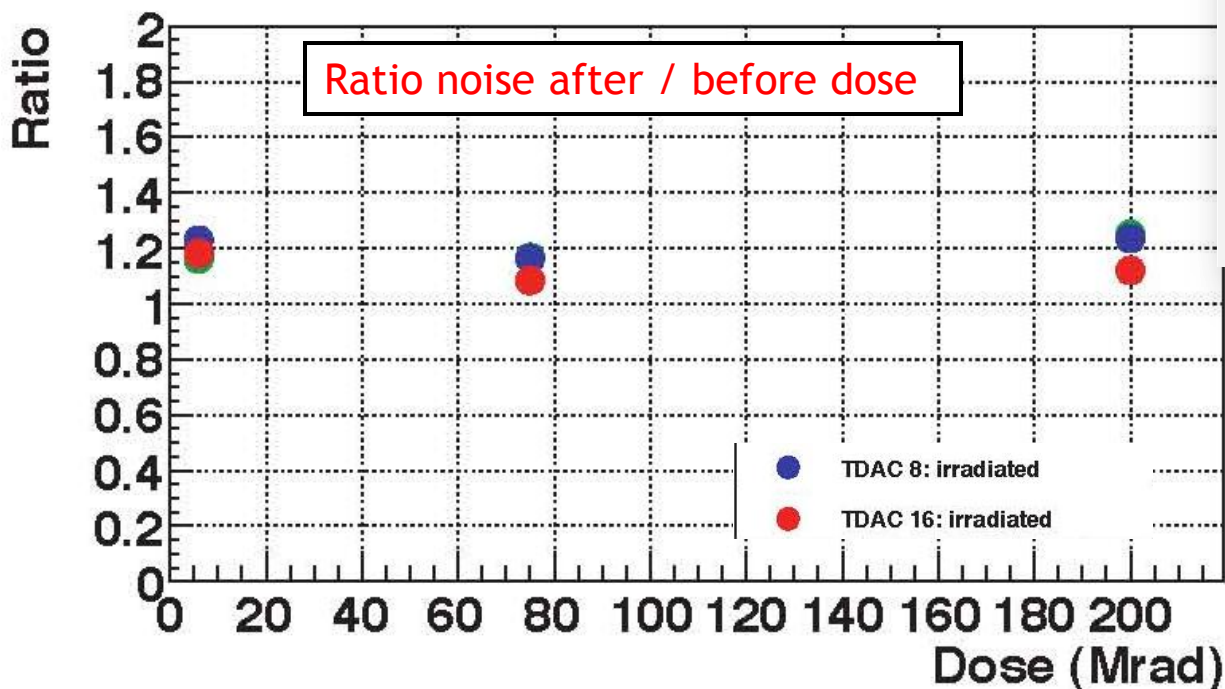


	FE-I3	FE-I4
Pixel size [μm^2]	50x400	50x250
Pixel array	18x160	80x336
Chip size [mm^2]	7.6x10.8	20.2x19.0
Active fraction	74%	89%
Analog curr [$\mu\text{A}/\text{pix}$]	26	10
Digital curr [$\mu\text{A}/\text{pix}$]	17	10
Analog Voltage [V]	1.6	1.5
Digital Voltage [V]	2.0	1.2
Readout [Mb/s]	40	160

Dose and noise



- ✓ Typical noise of the bare FE after calibration $\sim 110e^-$. Measured before and after irradiation for different DAC settings.
- ✓ 800 MeV proton irradiation at Los Alamos:
 - 6 / 75 / 200 MRad.

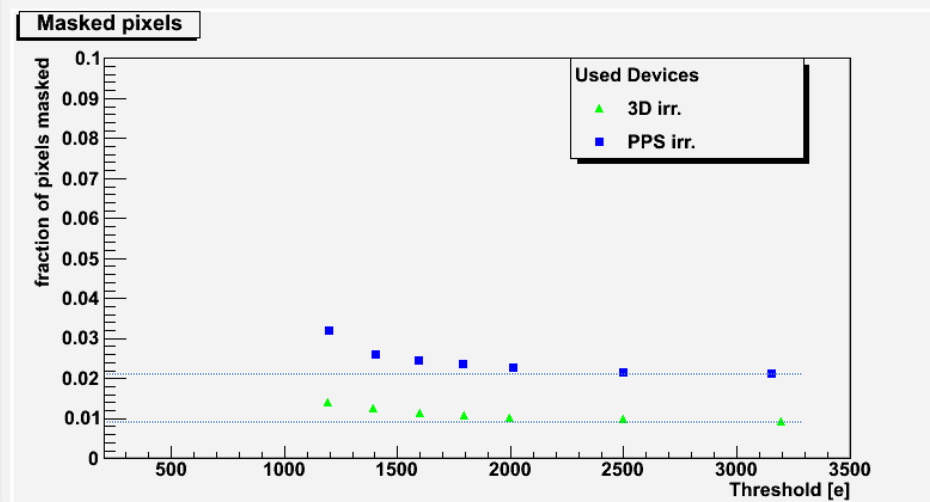
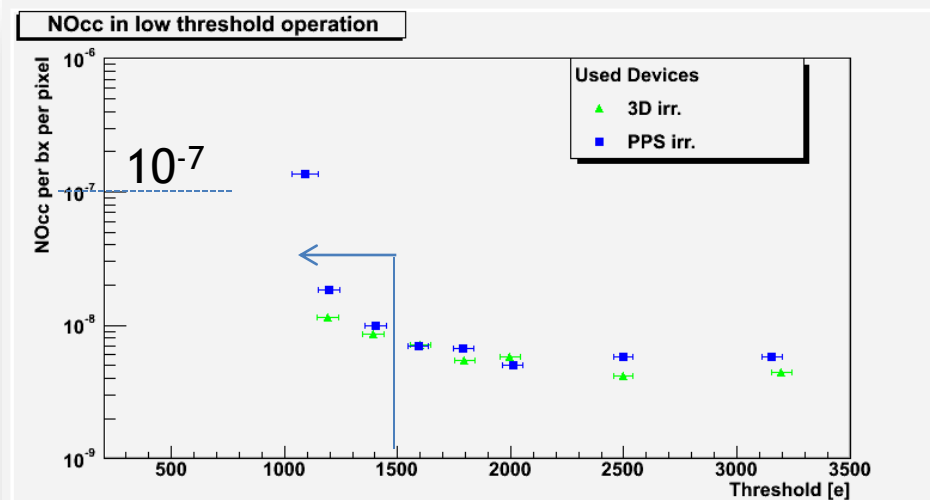


Low threshold operation



- ✓ Studies on PPS and 3D assemblies irradiated with protons to $5 \cdot 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$.
 - Noise occupancy increase when Threshold below 1500 e^- .
 - At 1100 e^- , occupancy is $\sim 10^{-7}$ hits/BC/pixel.
- ✓ Low threshold operation with irradiated sensors demonstrated!

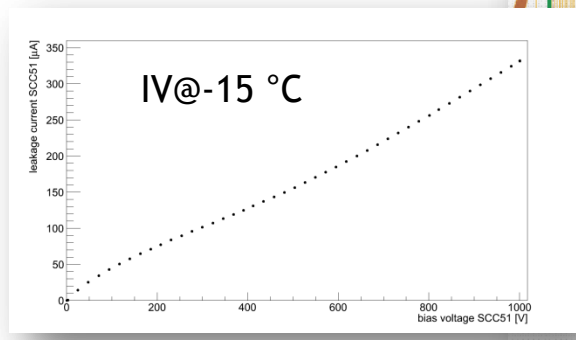
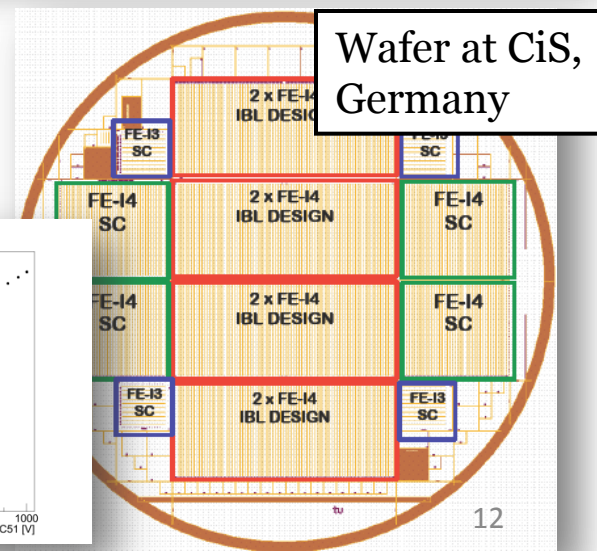
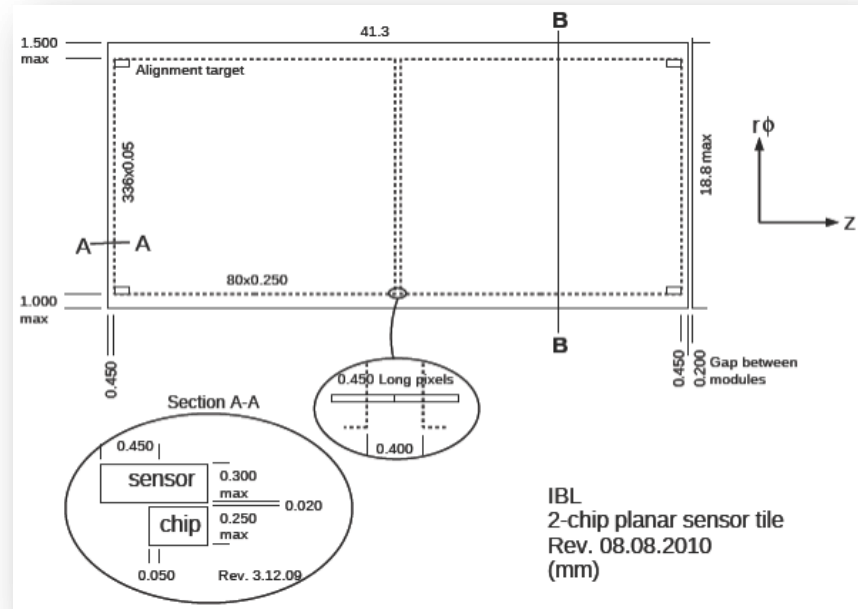
Masked pixel floor = digitally un-responsive pixels.



2-Chip Planar Sensor



- ✓ Main advantage:
 - All benefits of a mature technology (yield, cost, experience).
- ✓ Main challenges:
 - Low Q collection after irradiation,
 - Low threshold FE-operation.
 - High HV needed: important requirement for the services and cooling.
 - Inactive area at sensor edge.
 - Slim edge sensors.

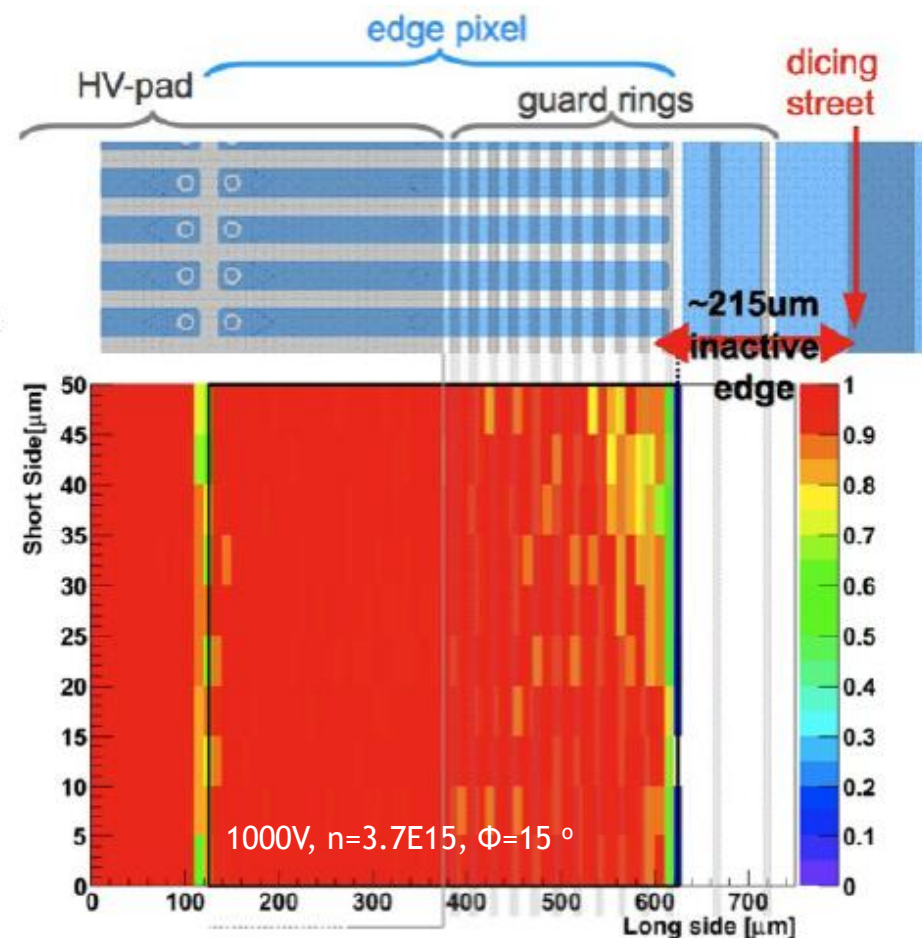
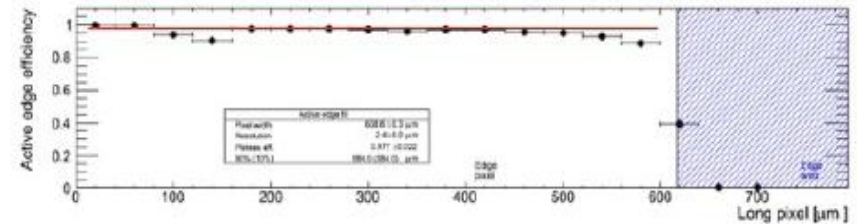


2-Chip Planar Sensor: Performance



✓ Final choice for the IBL design:

- Thickness is 200 μm . Best compromise between Charge collection and material budget.
 - n-in-n technology with $\sim 200 \mu\text{m}$ slim edge (is 1100 μm in the Pixel detector)
- ## ✓ Slim edge: 500 μm long edge pixels with guard ring shifted underneath on the opposite side from pixel implant.
- Only moderate deterioration. 250/200 μm of inactive edge before/after irradiation. Bring to total geometrical inefficiency of 98.3-98.5%.
- ## ✓ High efficiency ($>97\%$) for tracks at operation conditions (see next slide).

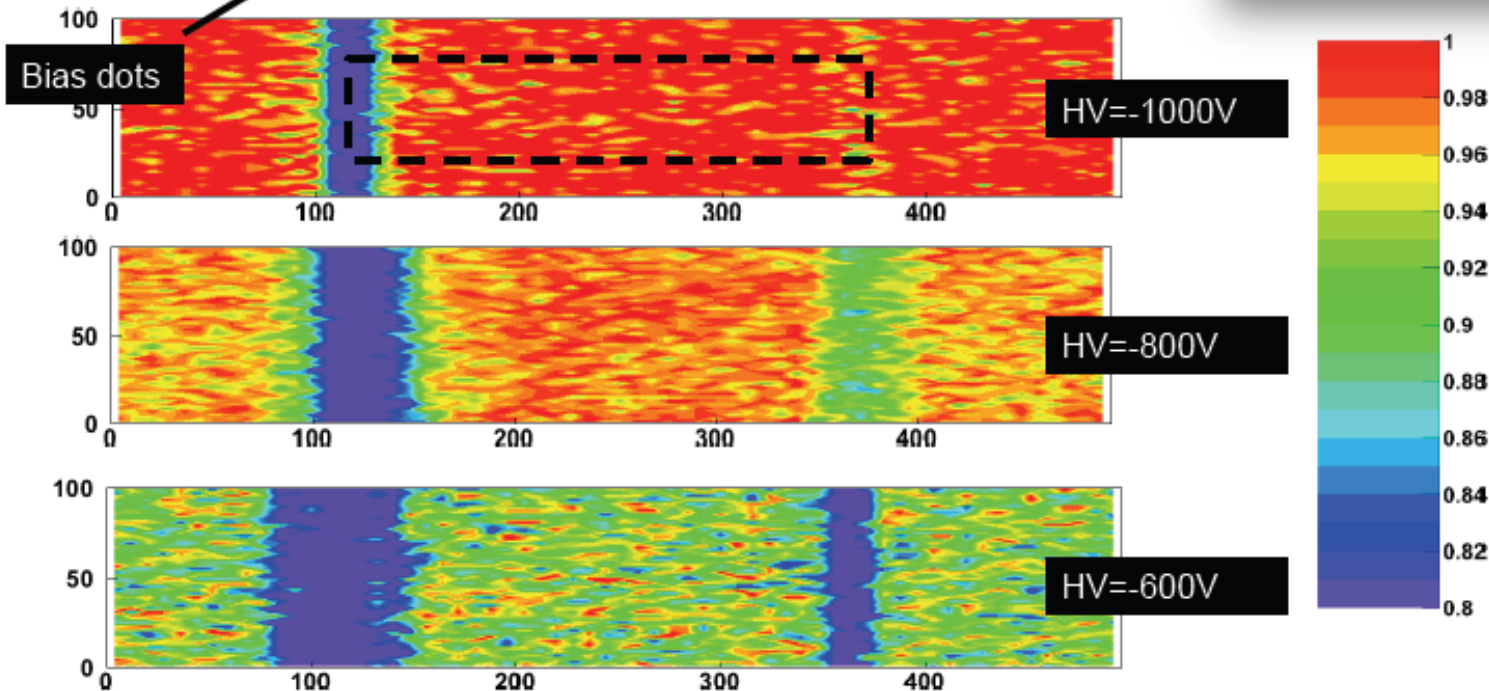
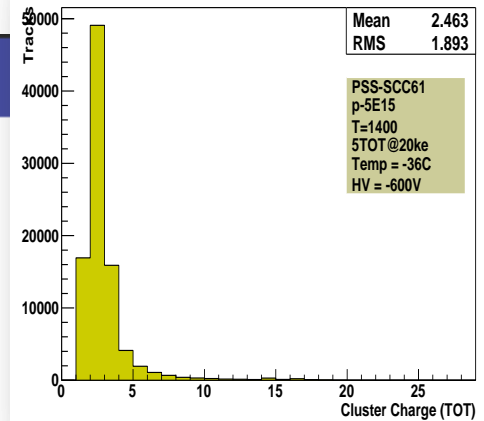
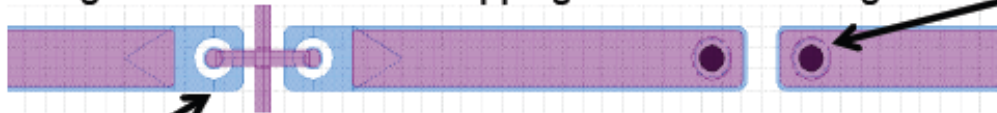


2-Chip Planar Sensor: Performance



SCC61: PPS 200 μ m, p -6E15, $\Phi=15^\circ$

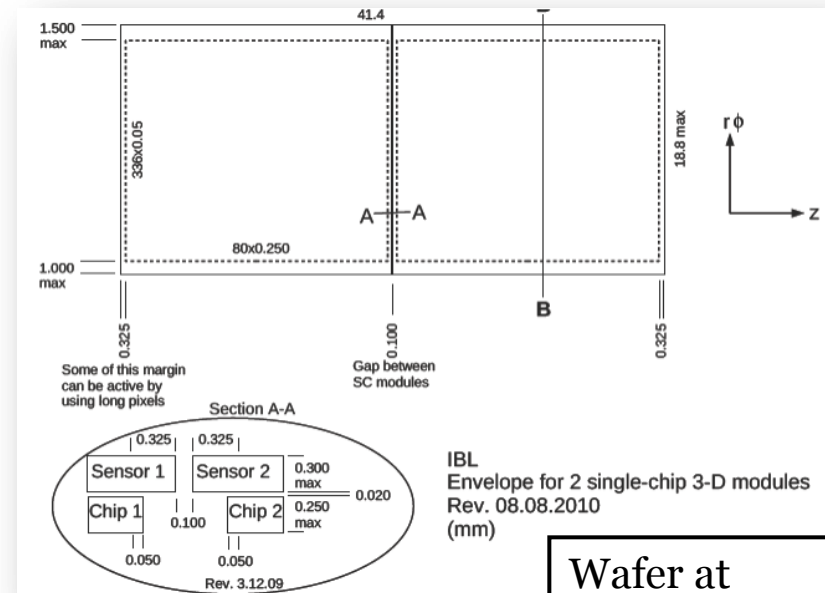
Cell Efficiency Maps: efficiency distribution within the pixel cells.
Pattern observed with FE-I3.
Efficiency loss at cell borders mainly due to charge sharing.
More charge loss on bias side: trapping in bias dots and grid.



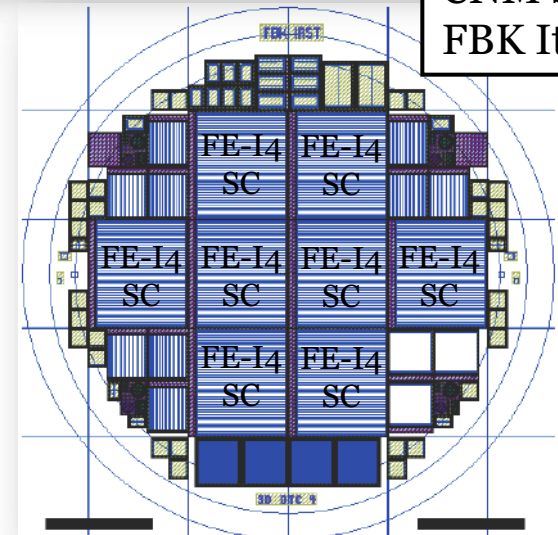
1-Chip 3D Sensor



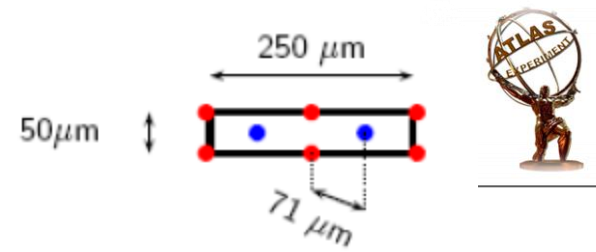
- ✓ Main advantage:
 - Radiation hardness.
 - Low depletion voltage (<180V).
- ✓ Main challenges:
 - Production yield.
 - In-column inefficiency at normal incidence.
 - Active edges and full 3D processing not established enough on project time scale.
- ✓ Two vendors CNM and FBK
 - Production schedule requires aggregate production



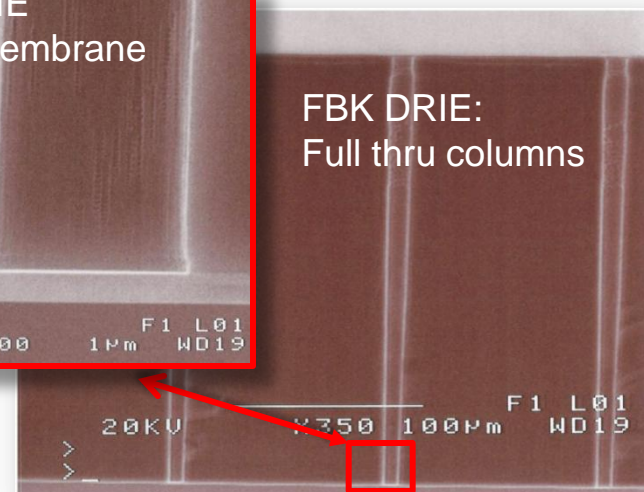
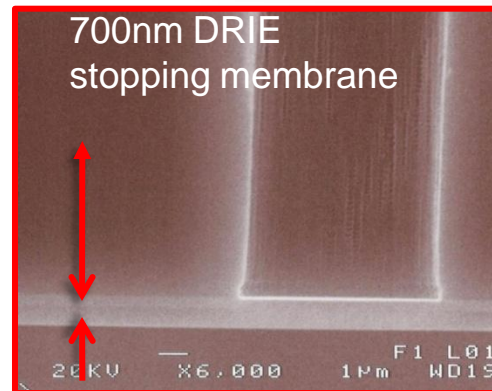
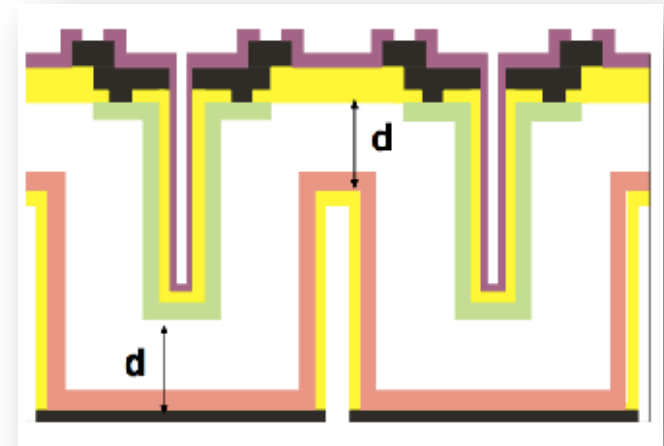
Wafer at
CNM Spain /
FBK Italy



1-Chip 3D Sensor



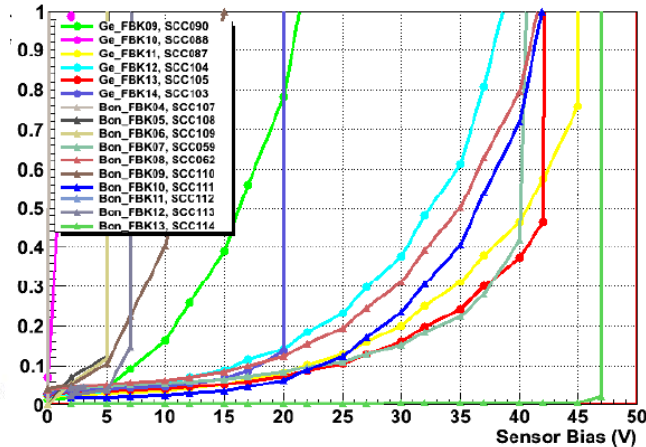
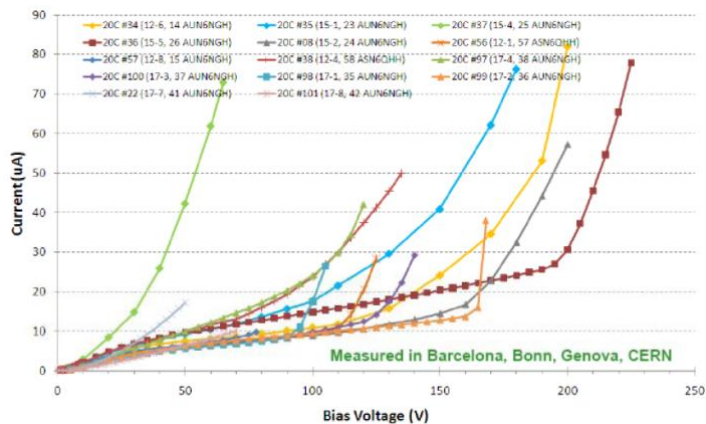
- ✓ Main advantage:
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 - Active edges and full 3D processing not established enough on project time scale.
- ✓ Two vendors CNM and FBK
 - Production schedule requires aggregate production.
 - Double-Sided full passing 3D, 2 electrodes per pixel
 - ~10 μm column diameter
 - ~70 μm interdistance
 - Wafer yield ~ 55%



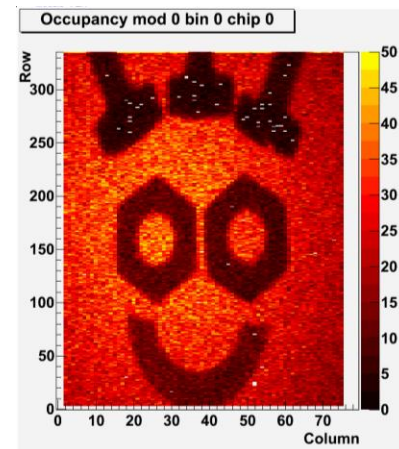
1-Chip 3D Sensor: Performance



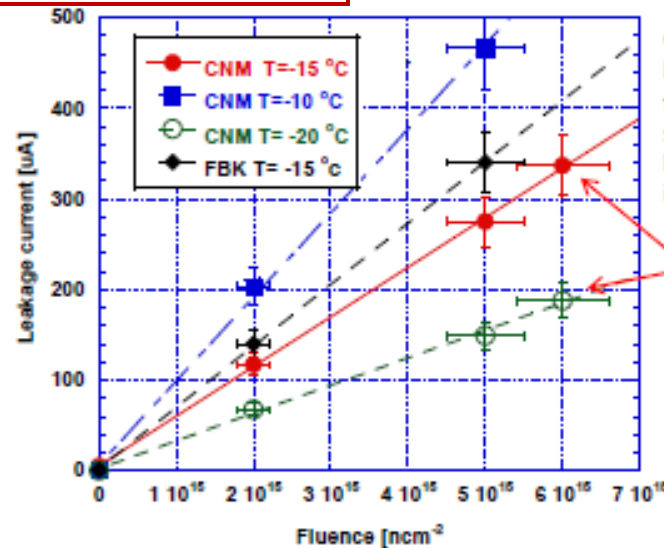
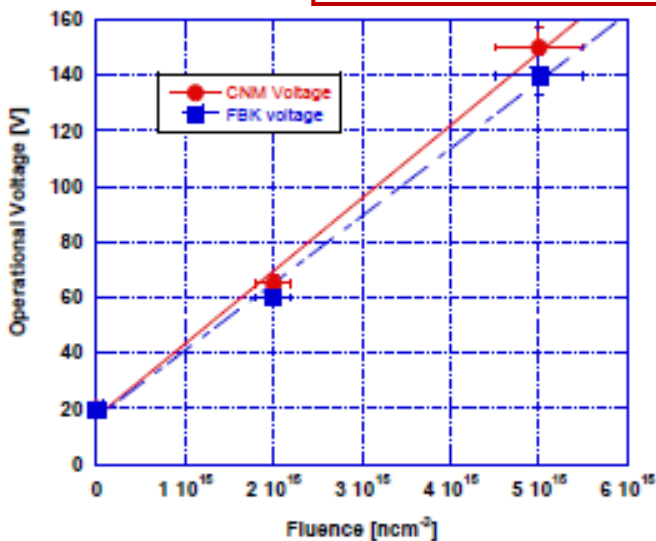
Leakage currents for CNM and FBK



Am source scan



Voltage and currents vs fluence



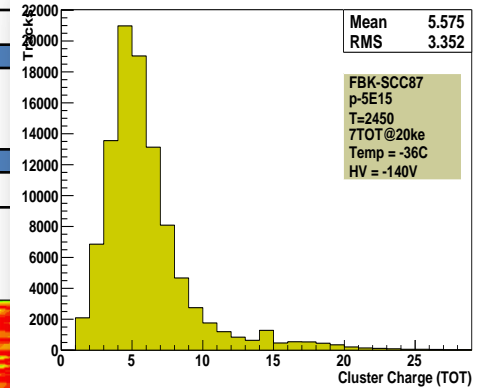
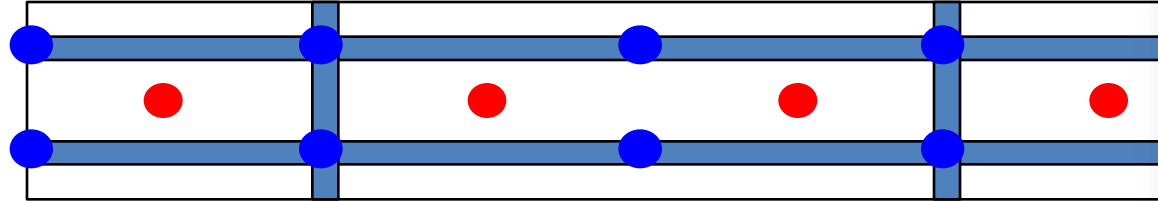
Confirms higher damage for second raw samples during last KA proton irradiation

CNM SSC97

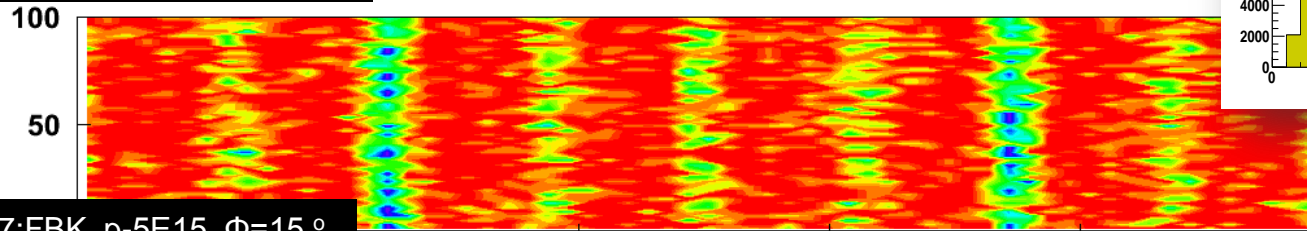
1-Chip 3D Sensor: Efficiency



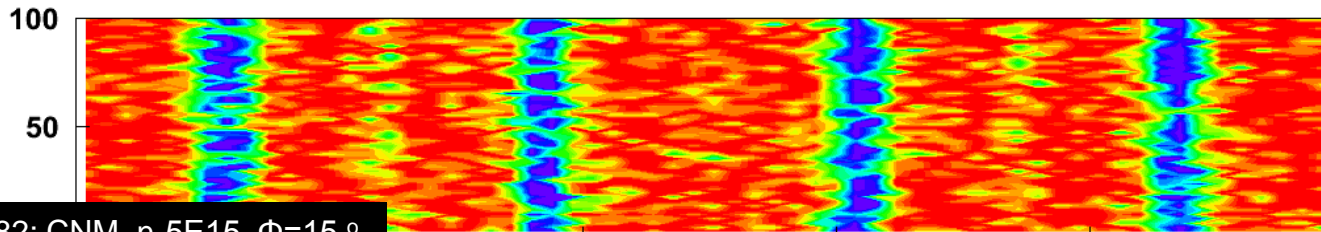
p-type Bias Electrodes n-type read-out Electrodes



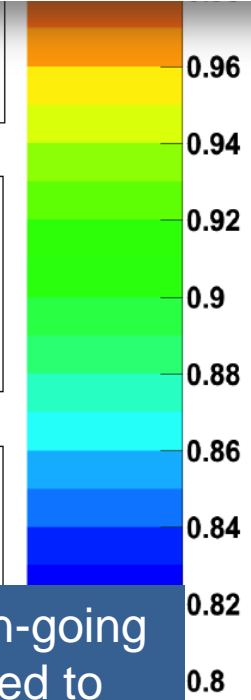
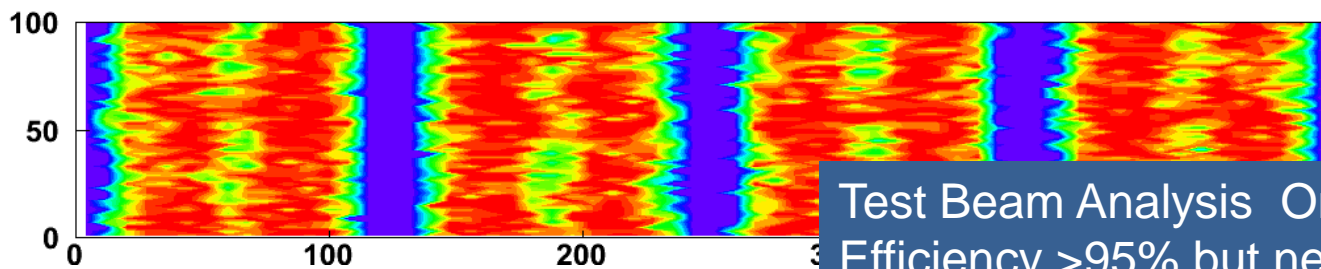
SCC97: CNM, p-5E15, $\Phi=15$



SCC87:FBK, p-5E15, $\Phi=15^\circ$



SCC82: CNM, n-5E15, $\Phi=15^\circ$

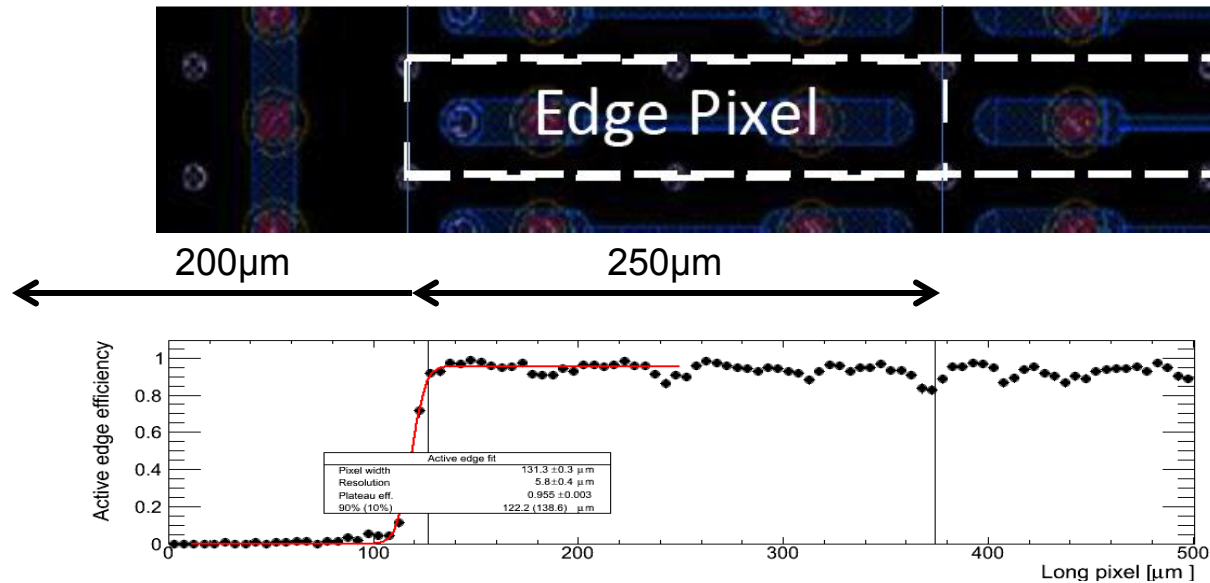


Test Beam Analysis On-going
Efficiency >95% but need to
Measure with lower threshold.

1-Chip 3D Sensor: Edge Efficiency



- ✓ For 3D sensor the edge pixel has a regular length.
 - Inactive area: 200 μm
- Actual efficiency extends:
 - 50%: 20-30 μm
- Effective inactive area from dicing: $\sim 200 \mu\text{m}$.
- Same for all 3D samples.

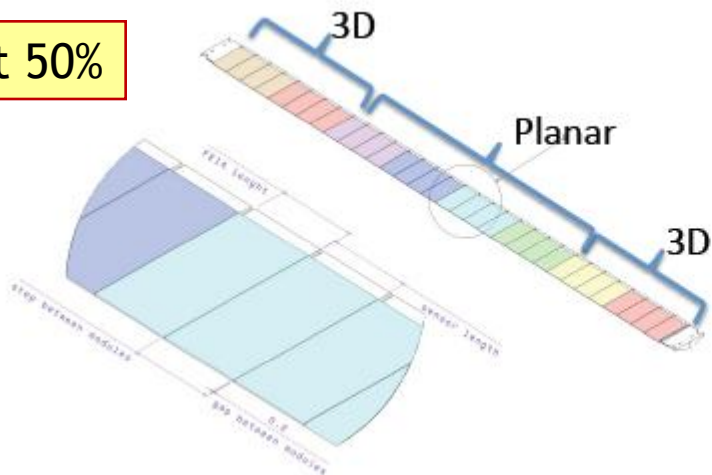


Sensor choice

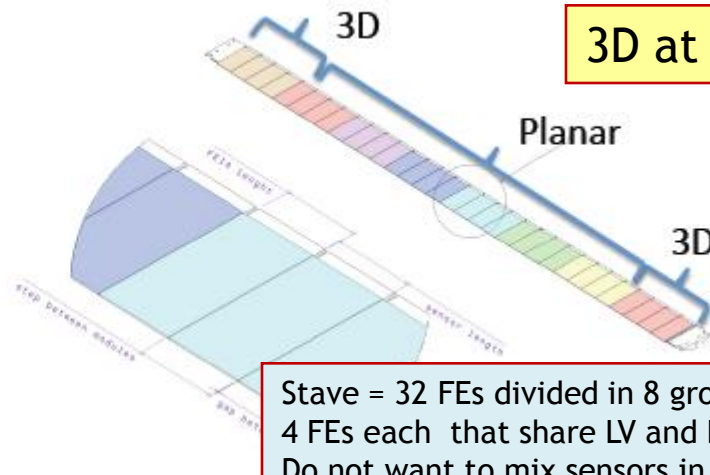


- ✓ Sensor Review hold on July 4/5. **Fresh News!**
 - The review panel found nothing is wrong in the 2 technologies.
 - Proposed a mixed scenario with both sensors in:
 - 3D technology to populate the forward region where the tracking could take advantage of the electrode orientation to give a better z-resolution after heavy irradiation
- ✓ Target to 25% coverage with 3D - Verify in February 12 where we stand then move up to 50%.
 - Anyhow Continue the production of the Planar to cover the whole IBL.

3D at 50%



3D at 25%

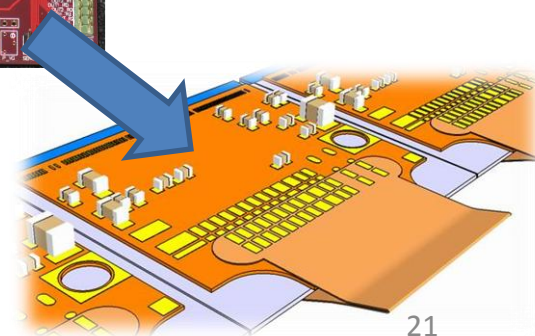
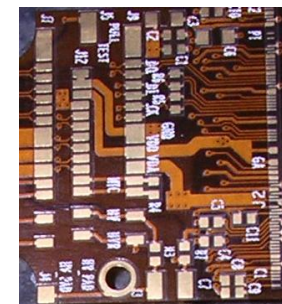
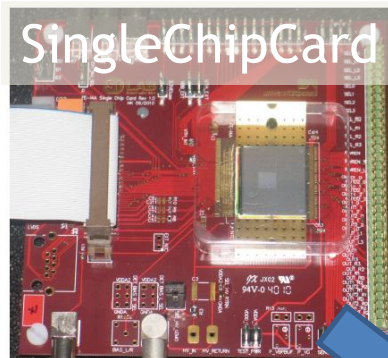
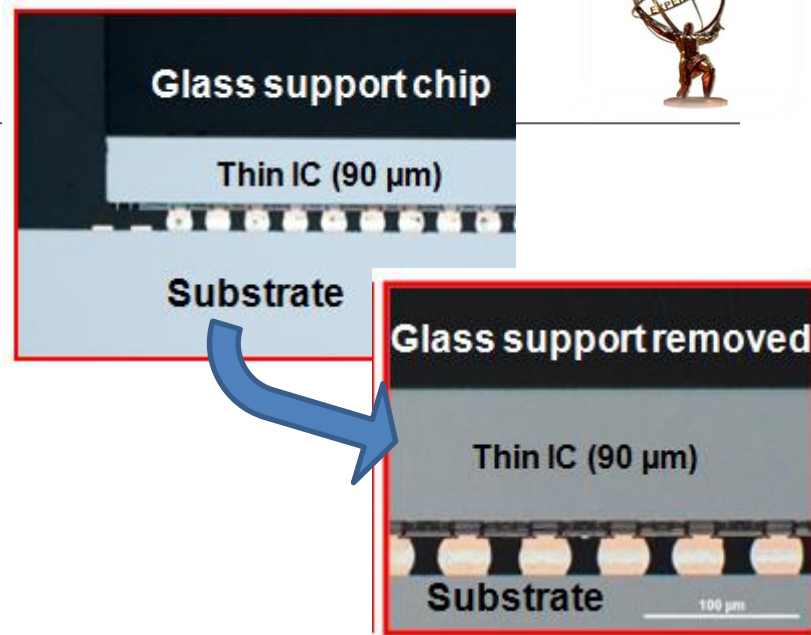


Stave = 32 FEs divided in 8 group of 4 FEs each that share LV and HV.
Do not want to mix sensors in a group.

Modules



- ✓ IBL modules preproduction with Planar and 3D sensors
 - Over 78 single-chip assemblies produced for the sensor qualification.
 - Many of those irradiated to check design requirements.
 - Bump bonding yield at IZM around 85%. Good for the start-up with FEI4.
- ✓ Now addressing thinner electronics
 - Thin (100-150 μm) FEI4 for a low X_0 module.
 - Safe bump-bonding requires max bend of $\sim 15\mu\text{m}$. Achievable with a minimal thickness of $450\mu\text{m}$. Use temporary glass handling wafer + laser de-bonding.
 - First devices produced and under tests.
- ✓ Module flex on top for final assembly
 - Up to now just used test card.

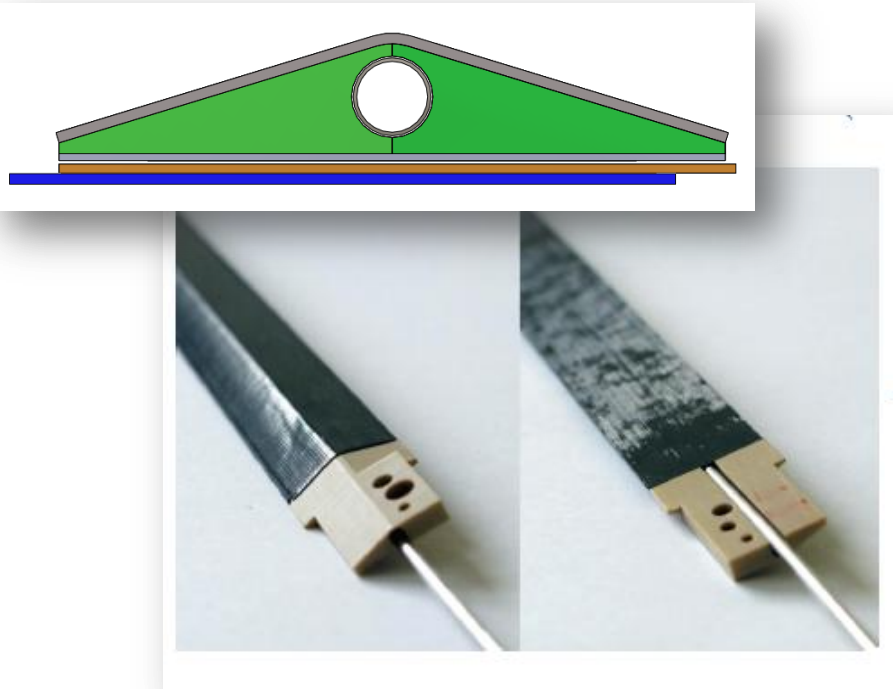


Stave



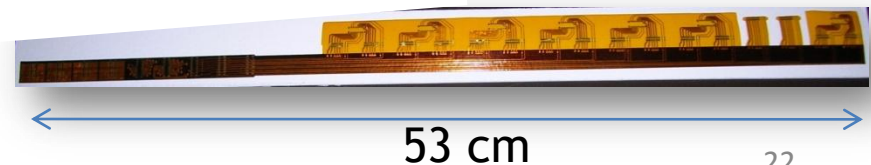
✓ Mechanical structure:

- Tested a large number of prototypes to find right balance between thermal performance, mechanical stiffness and reasonable X_0 .
- Shell structure filled with light (0.2g/cc) carbon foam for heat transfer to central cooling pipe (1.5mm ID Ti pipe 0.1mm thick)
- Cooled with CO2 system at -40C (~1.5kW total).



✓ Services on the back

- 500 μm Flex Al/Cu bus glued/laminated on the stave backside to route signals and power lines. (Al-only solution in parallel)
- The flex design include wings to be folded and glued to the modules.



Conclusions



- ✓ Tight schedule for installation in 2013 shutdown. On the critical path:
 - New revision of the FEI4 submitted in July and back in October.
 - Bump bonding with thin electronics.
 - Keep the material under control (1.5% X_0)

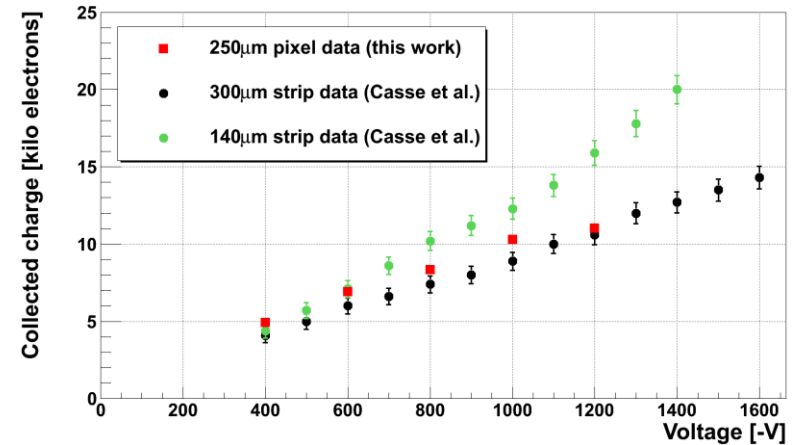
Activities	Starting	Ending
FEI4-B	July 11: Submission	Oct to Dec 11 for wafer tests
Bump bonding	Aug 11: pre-production	July 12: Completion
Module assembly	Feb 12: 1 st modules ready for loading	Oct to Dec 12 depending of sensor
Module loading	Feb 12: → 4 staves to be ready by Apr 12	Jan 13: Completion
Stave loading	Sep 12: starting with the 1 st available staves	Feb – Mar 13: Completion
Final tests and commissioning	Sep 12	Jul 13: IBL Installation
Pit Installation	July 13	Mar 14

Spares

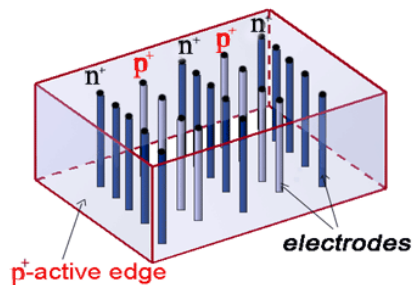




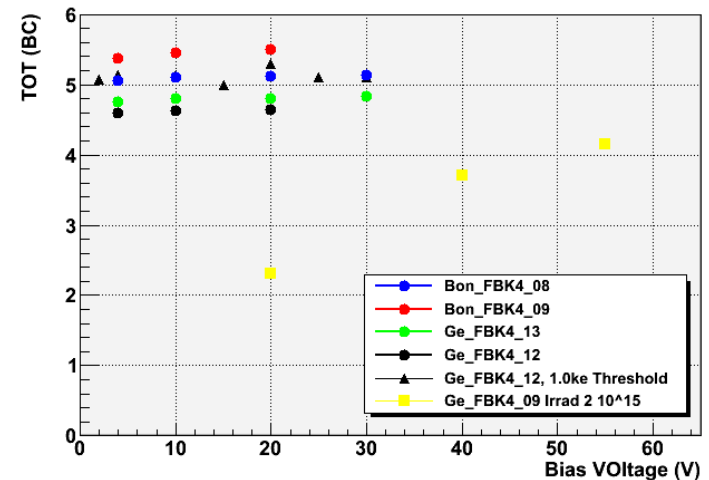
✓ Charge collection Planar



✓ Charge collection Am in 3D



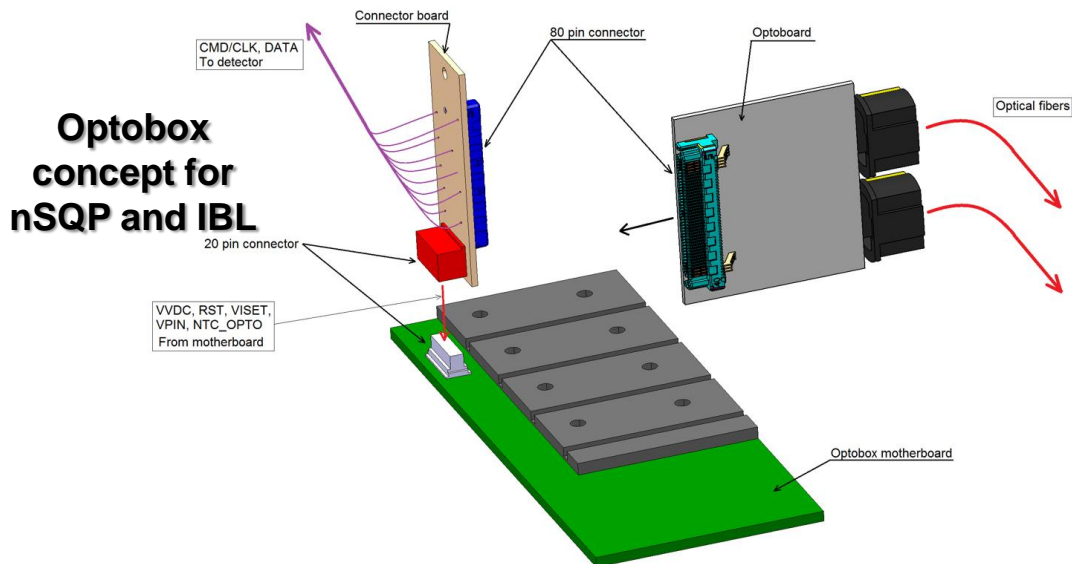
Am ToT vs HV



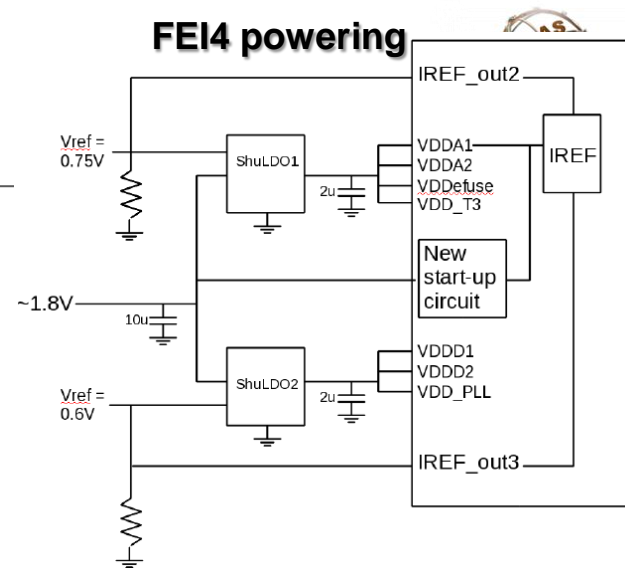
Sample	Fluence	ID	AI Board Temp(C)	HV(V)	I(μ A)	Thers hold (e)	Tilt Angle	Tracking Efficiency (%)	Charge Sharing (%)
PPS 200 μ m Slim Edge	n/a	40	-14	-100		2700	0	99.9/99.9	15/73.3
3D-CNM	n/a	55	-14	-20	0.7	1200	0	99.5/99.6	24/37.9
PPS 200 μ m Slim Edge	p-5E15	60	-14	400/600/800	324/290/555	1300	0	Data unusable (too high rate in Telescope)	
PPS 200 μ m Slim Edge	p-6E15	61	-36	-1000	160	1400	15	96.9	43.9
		61	-26	-800	260	1400	15	93.7	28.9
		61	-36	-600	57	1400	15	86.7	7.0
PPS 250 μ m Slim Edge	n-3.8E15	LUB2	-36	-1000	74	1100	15	99.0	43.5
		LUB2	-26	-800	100	1100	15	98.7	9.7
		LUB2	-36	-600	28	1100	15	97.8	14.1
		LUB2	-26	-400	40	1100	15	95.7	12.2
3D-CNM	p-5E15	34	-14	-140	150	1300	0	96.1/97.5	9.4/9.9
3D-CNM	p-6E15	97	~-36	-140	30	2950	15	97.4	22.1
3D-CNM	n-5E15	82	~-36	-160	27	2700	15	89.4	11.3
3D-FBK	p-5E15	87	~-36	-140	35	2450	15	95.3	39.5
3D-FBK	p-2E15	90	~-36	-160	34	3100	15	99.8	59.9

Off-detector

- ✓ **FE-I4 voltage regulators proposed to be set in partial shunt mode** to guarantee a minimal current. The goal is to limit transient voltage excursion.
- ✓ **First complete prototype of optobox in October**
- ✓ **ROD fabrication has started: 2 prototypes expected by next month**
- ✓ **ROD firmware design is ongoing**
- ✓ **The design of a full DAQ chain simulation environment has started**
- ✓ **BOC: prototypes expected by September**, then testing and redesign until the end of the year
- ✓ **RX plugin: investigation underway** to use commercial SNAP12 modules
- ✓ **Grounding & Shielding concept is now integrated** into the whole IBL detector



FEI4 powering



BOC block diagram

